



Attorney's Pocket No.: NECK 17.552 (100806-17282)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor : Hiroshi Tanabe
Title : METHOD FOR FORMING SEMICONDUCTOR FILMS AT
DESIRED POSITIONS ON A SUBSTRATE
Serial No. : 09/614,286
Confirmation No. : 2375
Filed : 07/12/2000
Examiner : Hiroshi Tanabe
Group Art Unit : 2813

Mail Stop: Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Comments on Statement of Reasons for Allowance

Sir:

The referenced application was allowed on, October 13, 2004. The issue fee due on January 13, 2005 is being paid concurrently herewith.

Applicant hereby acknowledges the Examiner's Reasons for Allowance. Applicant respectfully notes that there may be additional reasons for allowance that have not been specifically cited, and which may apply to various of the allowed claims, in addition to or instead of the cited reasons. Applicant respectfully suggests that notwithstanding the Examiner's Reasons for Allowance, it is believed that each of the allowed claims is patentable in its own


41293331 01

right and/or for other reasons raised during the prosecution and/or explained in the specification of this application.

To the extent that any statements regarding patentability of any claims allowed by the Examiner made by the Applicant or the Examiner in any document filed in this application are inconsistent with or not included in the Examiner's Reasons for Allowance, they are incorporated by reference herein

Any fee due with this paper may be charged on Deposit Account No. 50-1290

Respectfully submitted,



Michael I. Markowitz *Hassan A. Shakor*
Reg. No. 30,659 *53,922*

CUSTOMER NO: 026304
Telephone - (212)-940-8800
Fax: (212) 940-8986
Date: December 30, 2004
Docket No.: NECK 17,552 (100806-17282)

Certificate of Facsimile Transmission
I hereby certify that this paper is being facsimile transmitted to the Patent and Trademark Office on the date shown below

James J. Dada
Signature _____
Date *12/30/04*